



Correction: Design and Development of Oblique-Incident Interferometer for Form Measurement of Hand-Scraped Surfaces

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The original version of this article unfortunately contained a mistake. The following declaration text was missing.

Conflict of interest The authors declare no conflicts of interest.

The original article has been corrected.

The original article can be found online at <https://doi.org/10.1007/s41871-020-00089-w>.

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